



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**
Norio KIMURA et al. : Attorney Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Jeffrie R. Lund
SUBSTRATE POLISHING APPARATUS AND : **Mail Stop: AMENDMENT**
SUBSTRATE POLISHING METHOD

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Petition hereby is made for a two month extension of time to respond to the communication of
January 12, 2007.

The fee of \$450.00 is

(X) submitted herewith.

() to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition is
enclosed.

() Small entity status of this application is established by a Small Entity Status Assertion
which

() is enclosed.

() has been previously submitted.

Respectfully submitted,

Norio KIMURA et al.

By

Nils E. Pedersen

Registration No. 33,145

Attorney for Applicants

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

NEP/krq
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
June 1, 2007

06/04/2007 YPOLITE1 00000066 09864208
01 FC 1252

450.00 OP